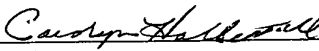


IN THE  
UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : To be assigned  
Applicant : Jui-Ping LI, et al.  
Filed : Herewith  
Title : Apparatus For Forming Film In  
Semiconductor Process And  
Method For Feeding Gas Into  
The Same Apparatus  
Prior Art Unit : 1763  
Prior Examiner : Karla A. MOORE  
Docket No. : 201056-9012

I, Carolyn Hothersall, hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date of my signature.

  
Signature

11-24-03  
Date of Signature

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT FOR DIVISIONAL APPLICATION**

Dear Sir:

Prior to the taking up of this application for examination, the application is amended,  
as follows:

**Amendment to the Specification** begins on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on  
page 3 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.